

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

5 Applicant(s): In Kwon Jeong

Serial No. 10/765,613

Filed: January 27, 2004

Group Art Unit: 3723

Confirmation No. 1365

Examiner: Wilson, Lee D.

For: APPARATUS AND METHOD FOR POLISHING SEMICONDUCTOR
WAFERS USING ONE OR MORE PIVOTABLE LOAD-AND-UNLOAD
CUPS

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO FINAL OFFICE ACTION

20 Sir/Madam:

In response to the Final Office Action mailed on March 16, 2007, please
consider the following remarks, which begin on page 2 of this paper.

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